

# NEWS RELEASE

Hitachi High-Tech

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Hitachi High-Technologies Corporation

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## **Dr. Hidehito Obayashi to receive 2010 IEEE Ernst Weber Engineering Leadership Recognition**

—The first Japanese recipient of the award for his contributions to the continued miniaturization of silicon wafers through the development and implementation of CD-Measurement SEM—

Dr. Hidehito Obayashi, President and Chief Executive Officer, Hitachi High-Technologies Corporation, is being honored by the IEEE\* with the 2010 IEEE Ernst Weber Engineering Leadership Recognition. The award was established in 1985, and later renamed in 1996 to honor Ernst Weber, first President of the IEEE. The award is presented to the person who has demonstrated exceptional managerial leadership in the field of electrical engineering. Dr. Obayashi is the first Japanese recipient of the award.

Dr. Obayashi proposed the use of a Scanning Electron Microscope (SEM) over a traditional optical microscope to accurately measure the microscopic circuit patterns of semiconductors, and developed the world's first CD-Measurement SEM\*\* in the 1980s. From 1996, he taught the principles and applications of the electron microscope as a Visiting Lecturer at the University of Tokyo. He has also contributed to the development and implementation of CD-Measurement SEM as Vice Chairman of the Semiconductor Equipment Association of Japan (SEAJ), and was awarded the Okochi Memorial Production Prize for the development and practical application of CD-Measurement SEM in 2007.

The award, sponsored IEEE, recognizes Dr. Obayashi for his customer-oriented engineering and managerial leadership in the field of SEM, including the creation and development of CD-Measurement SEM for LSI manufacturing. The CD-Measurement SEM is used in semiconductor device development and production lines all over the world, and plays a vital role in the miniaturization of circuit patterns and process yield control.

The award will be presented on June 26, 2010 at the IEEE Honors Ceremony in Montreal, Quebec, Canada.

\*Institute of Electrical and Electronics Engineers, Inc., the world's largest technical professional association. The IEEE has more than 395,000 members in more than 160 countries.

\*\*Critical Dimension Measurement Scanning Electron Microscope

### **Comment from Dr. Obayashi**

It is a great honor and pleasure for me to receive the IEEE Ernst Weber Engineering Leadership Recognition. I am indebted to customers around the world for their support and use of the CD-Measurement SEM over the years, and to the efforts of the Hitachi High-Tech staff in charge of development, sales, and after service who continuously try to satisfy the needs of those customers. It is your effort and support that has made this award possible.



Dr. Hidehito Obayashi, President and Chief Executive Officer,  
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